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ADE 6034 Wafer Measurement

Measure wafer thickness Variation (TTV), Flatness, Bow and Warp

ASSET#3428

REQUEST QUOTE →

ADE EpiScan 1000

High-speed film thickness measurement and mapping tool designed specifically for leading edge characterization of advanced, thin epi. **ASSET#4031**

ADE Ultra Gage 9500

Stress/Thickness Measurement. **ASSET#3842**

ADE Ultra Gage 9700

Stress/Thickness Measurement. **ASSET#3543 SOLD**

AG Associates Heatpulse 610 Rapid Thermal Processor

PC Controller. **ASSET#3941**

AG Associates RTA Heatpulse 2101

Rapid Thermal Annealer System - Capable of 3" to 5" Wafers. **ASSET#3289**

AG Heatpulse 8108 RTP System With EZ-DTC

Rapid Thermal Annealing System. Capable 4" to 8" wafers. **ASSET#4003**

AG Heatpulse 8808 RTP System With EZ-DTC

Rapid Thermal Annealing System. Capable 4" to 8" wafers. **ASSET#4007**

AMEL Instruments Model 2049

3 Units Available **ASSET#4032-4034**

AMEL Instruments Model 2053

ASSET#4035

Agilent 54622D Mixed Signal Oscilloscope Mega Zoom

ASSET#4036

Atcor CRD-2410

Box Washer. **ASSET#3111P**

Bay Voltex HS 0550-AC-SX-ENL

Recirculating Chiller **ASSET#3112**

Bay Voltex LT-1650-WC-DI-AM

Recirculating Chiller **ASSET#3449**

Blue M DCC 206C

Clean Room Oven **ASSET#3508**

Blue M DCC-256-B-MP550

2 Units Available. **ASSET#3345&3344**

ASM Ex. 1018
IPR Petition - USP 7,808,396

Blue M Model DCC-146C	Clean Room Oven (2 units) ASSET#3507,3294
Blue M Oven	Model: CW-190G-MP2. ASSET#3907 SOLD
Blue M Ultra Temp 6680 OV	ASSET#3812 SOLD
Branson / IPC S3000 Barrel Stripper	2" to 6" Wafer Capability. ASSET#3800
Branson 1510 UltraSonic Cleaner	Chamber 6" x 6" x 4" deep. ASSET#4037
Brewer Science Cee 100 System	The 100 series spincoaters are reliable and precise spinners mounted in a compact stainless steel benchtop unit. System setup as developer.
Brewer Science Cee 100 System	The 100 series spincoaters are reliable and precise spinners and hotplate module. ASSET#3911,3912
Budzar Ice	Chiller System ASSET#3431
COMDEL CLX-600	RF Generator / 400KHz-LF. Two units available. ASSET#3951,3552
Canon MPA 500 Projection Mask Aligner	Auto Feeder: Single, cassette to cassette, backside wafer handling. ASSET#3942
Canon MPA 600FA	Mirror Projection Aligner. SOLD
Chemical Safety Tech	Horizontal Quartz Tube Cleaner ASSET#3382
Chemical Safety Tech ET-4/1-VTBW	Polypropylene fumehood parts cleaning system ASSET#3383
EG&G; Instruments 7265 DSP Lock-in Amplifier	2 Units Available. ASSET#4038,4039
EG&G; Instruments Princeton Applied Research Potentiostat / Galvanostat Model 263A	ASSET#4040
ENI ACG-10	Solid State RF Generator ASSET#3469
ENI ACG-10B	Solid State RF Generator. Especially developed for MRC Sputtering Tools ASSET#3132
ENI HF-1	Power Generator. ASSET#3453
Electrotech LF-24	Solid state RF Power Generator. ASSET#3468
Estek Wis 600 Inspection System	Wafer Surface Analysis System for 3" to 6" wafers. ASSET#3844

FEI 851I CD SEM	Scanning Electron Microscope ASSET#3990
FSM 8800	Film Stress Measurement System. Up to 8" capability. ASSET#3843
Fluoroware HTC 8000	Cassette/Box Washer ASSET#3940
Four Dimension Movec 280	Four Point Probe Resistivity System ASSET#3930
Fusion, 200 PCU POLO	Photostabilizer System ASSET#3494 SOLD
GaSonics AE 2001	Single wafer down-stream isotropic etch system. ASSET#3908
GaSonics Aura 1000	Cassette to Cassette Single Wafer Photoresist Asher. Capable 3" to 6" Wafers ASSET#3375,3376,3497,3803
GaSonics Aura 2000LL	Cassette to Cassette Single Wafer Photoresist Asher. Capable 5" to 8" Wafers ASSET#3139P
GaSonics Aura 2000LL Etcher	8" Cassette to Cassette Single Wafer Etcher. ASSET#4016
HP 8904A Multifunction Synthesizer DC-600 kHz	ASSET#4041
Hach One Laboratory PH/Meter	ASSET#4042
KLA 2131 Upgraded to a 2132 High Speed Multilayer Wafer Inspection for Process Defects	Inspection Modes for Arrayed and Random Patterns- 4" to 8" Water Capability 2 AVAILABLE. ASSET#3542, 3854
KLA 2132 High Speed Multilayer Wafer Inspection for Process Defects	Inspection Modes for Arrayed and Random Patterns - 4" to 8" Water Capability ASSET#3846
KLA 2606 Review Station	Review Station with Nikon BD Plan. ASSET#4022
KLA-TENCOR SURFSCAN 6220	NON-PATTERNED WAFER SURFACE INSPECTION SYSTEM. ASSET#3403
KLA-Tencor P20H Long Scan Profiler	Cassette to Cassette Profilometer. Capable 4" to 8" wafers
KLA-Tencor Alpha Step 200	Profiler with 5A vertical resolution and 160KA range, stage movement XY movement 4"x3", auto leveling. Asset # 3538
KLA-Tencor Alpha Step 500 Profilometer	Wafer Profiler System. Capable 4" to 8" wafers. ASSET#3927
KLA-Tencor Flexius FLX-5200	Thin Film Stress Measurement Instrument. Accurately Measures the

changes, created by deposition of a stressed thin film, in the radius of curvature of the substrate.

ASSET#3954

KLA-Tencor Flexus 2350FP

Thin Film Stress Measurement for substrates 5" to 12". **ASSET#3397**

KLA-Tencor M-Gage 300

Non-Contact Metallization Monitor. **ASSET#3541**

KLA-Tencor P-1 Long Scan Profiler

Wafer Size: 3" to 8" wafer. **ASSET #3931**

KLA-Tencor P-2 Long Scan Profiler

High sensitivity surface profiler measuring roughness, waviness and step height. 2" to 8" Wafer Capability **2 SYSTEMS AVAILABLE. ASSET#'s 3833, 3834**

KLA-Tencor P20H Long Scan Profiler

Measurement of vertical features ranging from 100A to 0.3mm

KLA-Tencor SP1 Classic Single Cassette System

Wafer Surface Analysis System. Capable 4" to 12" wafers. **ASSET#3938**

KLA-Tencor SP1 Classic Single Cassette System

Wafer Surface Analysis System. Capable 4" to 12" wafers. **ASSET#3938**

KLA-Tencor Surfscan 354

Wafer Contamination Monitor **.ASSET#3814**

KLA-Tencor Surfscan 4500

Surface Particle Inspection Analyzer. **ASSET#3828**

KLA-Tencor Surfscan 5000

Surface Particle Inspection Analyzer. Measures up to 8" wafers **ASSET#3462**

KLA-Tencor Surfscan 6220

Converted from a 6200. Non-Patterned Wafer Surface Inspection System - Can accommodate wafer from 2" to 8" diameter. **ASSET#3404**

KLA-Tencor Surfscan 6220

Non-Patterned Wafer Surface Inspection System - Can accommodate wafer from 2" to 8" diameter. **ASSET#3403**

KLA-Tencor Surfscan 7000

Patterned Wafer Particle Inspection System. 4" to 8" wafer size **2 AVAILABLE. ASSET#3210, 3208**

KLA-Tencor Surfscan 7200

Patterned Wafer Particle Inspection System for Substrate Size: 4" to 8" **3 AVAILABLE. ASSET#'s 3209, 3207, 3499**

KLA-Tencor Surfscan 7700

Patterned Wafer Inspection System. Capable 4" to 8" wafers. **ASSET#4002**

KLA-Tencor Surfscan SP1

Capability up to 300mm.

ASSET#3937

KLA-Tencor TF-1	Film Thickness Measurement System - Substrate Size: 4" to 8" ASSET#3300
KLA-Tencor TF-2	Film Thickness Monitor. ASSET#3299
Karl Suss CIC 1000	1000 Power Supply for Karl Suss Mask Aligners. ASSET#3917
Karl Suss MA- 56	Mask Aligner-Exposure System. ASSET#3263P
Karl Suss MA- 6	Mask Aligner-Exposure System with Backside IR.Karl Suss MA-6 BSA/IR With Backside IR capability. SOLD
Karl Suss MA-150 Cassette to Cassette Mask Aligner	Wafer Size Up to 6" diameter / Mask Size up to 7". ASSET#4029
Karl Suss MA150M	MA150M-BSA With Backside Optical. Serial # 105 w/ Auto Aligner. ASSET#3829
Karl Suss MJB3 Mask Aligner-Exposure System	Holder for 4" square mask allows nearly 78 mm diameter of wafer exposure. ASSET#3928
Karl Suss RA120M Scriber	Process Description: Scribing a wafer is a method of die separating. A diamond-tipped scribe is dragged across a wafer creating a scratch in the wafer surface. When the wafer is stressed, the wafer separates along the scribe lines. The breaks follow the crystal structure of the wafer, creating a right-angle edge on the die. ASSET#3950
Keithley 2701 Ethernet Multimer / Data Acquisition System	ASSET#4043
LEDE HTC 4000 Box Washer	Cassette / Box Washer. ASSET#3504
Leitz Ergolux	Unit includes Vario-Orthomat 2 Camera. ASSET#3856
Leitz Ergolux Microscope	Unit includes Camera. ASSET#3874
Linberg / Blue Oven	Max Temp: 300c. ASSET#3996
Lindburgh 55035	Tube Furnace. ASSET#3255
Lumonics Wafer Mark II	Laser identification system capable of handling 2" to 6" wafers. ASSET#3847
Mactronix AWS BWI 600 Microscope Loader / UV Inspection System	Programmable Wafer Sampler. ASSET#3926
Matrix System One	Photoresist Stripper. ASSET#3152P

Matrix System One 102	Photoresist Stripper. ASSET#3151
Micro Automation 1006	Programmable Micro Dicing Saw Capable of 3" to 6" Wafers. ASSET#3156
Micro Automation 1100	Programmable Micro Dicing Saw Capable of cutting 2" to 6" Wafers. ASSET#3503
Nanometrics 4150	Film Thickness Measurement & Mapping System 4" to 8" Wafer Capability. ASSET#3849 SOLD
Neslab CoolFlow RTE-221	Refrigerated Bath Circulator. ASSET#3446
Neslab DI Max	ASSET#3918
Neslab HX 150 Recirculating Chiller	Recirculating Chiller. 17 AVAILABLE. ASSET#3869
Neslab HX 300 Recirculating Chiller	Recirculating Chiller. ASSET#3892
Neslab RTE-140	Refrigerated Bath/Circulator. ASSET#3893
Nikon Metaphot Microscope	6" Stage. ASSET#3854
Nikon Optistation 3A	Automatic wafer inspection system for 4" to 6" wafer. ASSET#3851
Olympus BH2 – UMA Microscope	Inspection Microscope w/Camera - 2" to 12" Water Capability ASSET#3855
Ontrak System Inc. DSS-200 Series II SIII	Double Sided Scrub Track. Capable 4" to 8" wafers
Pacific Scientific SC100	Brushless Bernomotor Velocity Controller. 2 AVAILABLE ASSET#3466,3467
Perkin Elmer 2000	FTIR Spectrophotometer. ASSET#3405
Perkin Elmer 300 Micralign	Projection Mask Aligner. Capable of 3" to 5" Wafers. ASSET#3172
Perkin Elmer 4410 Sputtering System	Main Processing System with Load Lock. ASSET#3789
Phoenix V4	Wafer Transfer System. ASSET#3402
Prometrix FT-530	Film Thickness Mapping System. ASSET#3919
Prometrix FT-650	Film Thickness Mapping System. ASSET#3920

Prometrix RS35/c	Prometrix Omnimax.RS35/c Reistivity Mapping System. ASSET#4009
Prometrix RS35C	Resistivity Mapping System. ASSET#3933
Prometrix RS35C Resistivity Mapping System	Capable 4" to 8" wafers. ASSET#4009
Prometrix RS55 Resistivity Mapping System	Four Point Probe Resistivity Mapping System. Capable 2" to 8" wafers. ASSET#4008
Prometrix SM300 Film Thickness Mapping System	Four Point Probe Resistivity Tester.Maximum wafer size 200mm. (2 units) ASSET#4001,4000
RIGAKU 3630	WAFER SIZE: 4" TO 8". ASSET#3963
Rudolph Auto EL IV	Ellipsometer. ASSET#3261
Rudolph Research FE-III	Focus Ellipsometer. ASSET#3943
SVG 8600 Series Track System	Photoresist Coater / Developer Track Unit - 3" to 6" Water Capability. ASSET#3895
Schlumberger IVS 120	Overlay Measurement Inspection System. SOLD
Seiko D-Tran TT4000SC	Robotic Transfer Loader System with CCD Camera 3 AVAILABLE ASSET# 3269P, 3270P, 3271P SOLD
Sekidenko Model 4000 Data Acquisition System	2 Units Available. ASSET#4044,4045
Semitool 860-S	Spin Rinse Dryer - Accomodates 8" wafers. ASSET#3524
Semitool WST306	Water Soluble Develop Strip Tool. 3" to 5" wafers. ASSET#3526
Sloan Dektak II Precision Surface Profile Measuring System	2" to 6" Water Capability. ASSET#3850
Sloan Veeco 3030	Surface profiler with motorized and programmable 6"x3" xy stage travel. ASSET#3901
Solid State Measurements, Inc SSM 5130 CV System	Wafer diameter from 200 mm to 300 mm The SSM 5130 fully automatic mapping system provides a variety of electrical characterization measurements for non-patterned wafers used in epitaxial silicon production and front-end semiconductor processing. ASSET#4047

Solitec 8260-CB	Coat/Vacuum Bake. ASSET#3535
Sorgel Power Supply	3-phase insulated transformer. ASSET#3321
South Bay Technology 360	Diamond Wheel Saw. ASSET#3481
Spiricon InGaAs	IR Camera System. ASSET#N/A
TBM Company VLT 500 Chemical Freezer	26" W x 20" H x 16" D. ASSET#3451
TEL 580LC	Cassette to Cassette Etcher. Capable 3 to 6" Wafers. ASSET#3496
Technics 800 Series	Micro RIE Etcher. ASSET#3414
Technics Micro-RIE 85 Series Etcher	Manual operation with digital readout. ASSET#3414
Tegal 1512	RIE/Plasma Aluminum Etcher. ASSET#3348
Tegal 801	Plasma Inline Wafer Etcher. Capable of 3" to 5" Wafer. ASSET#3198
Tegal 903	Cassette to Cassette Single Wafer Plasma Etcher - Capable of 3" to 6" Wafers ASSET#3401
Tegal GCA Chiller	Circulating System for 903e. ASSET#3837
Tencor NC-110 Non-Contact Resistivity System	Measures complex aluminum and tungsten multilayer metallization schemes such as TiN/Al/TiN or W/TiN. Realistic process control by measuring actual product wafers. ASSET#4020
Tencor Surfscan 6220	Surface Particle Inspection Analyzer. Converted from a 6200.
Thermco MB-71	Laboratory Diffusion Furnace. ASSET#3488
Ultratech 602	Mask Cleaner. ASSET#3461,3474,3945
Ultratech UltraStep 1500	Big Field Projection Stepper with Autoloader. ASSET#N/A
Ulvac UNA-2000	Damage Free Ashing System. ASSET#3238,3239
VCR Group D500i	Dimpler TEM Specimen Preparation System. ASSET#3250
Varian 843	Ratiomatic Ionization Gauge Controller. ASSET#3455
Varian VFW287081	Multi-range DC Sputtering System. 3

**AVAILABLE. ASSET#3216, 3218,
3217**

Veeco Dektak II Surface Profiler	Measurement Range (full scale): 500A t 655,000A (50nm to 65,500nm). ASSET#3850
Verteq 1600 SRD Single Stack	Low Particulate Rinser/Dryer - 3" to 6" Water Capability. ASSET#3832
Verteq 1800 SRD Single Stack	Low Particulate Rinser/Dryer- 4" to 8" Water Capability. ASSET#3831
Verteq SRD 1600-3	Low Particulate Rinser/Dryer for up to 6" wafers. ASSET#3525
Vibration Isolation Table	All Stainless Steel Vibration Table. ASSET#3955,3956,3957
WED Loader AUL	Autoloader for microscopes ASSET#3108,3106,3107
WED MarcoSpec	Programmable Wafer Sampler. ASSET#3929
WED Micro Loaders	Autoloader for microscopes
Yield YES 10	Image Reversal System. ASSET#3505
Yield YES LPIII - M3	Vapor Prime Oven System. ASSET#3506
Yield YES R-3	Plasma Cleaning System. ASSET#3966
Zeiss IM-12 Wafer Loader	Microscope Wafer Loader. Capable up to 200mm Wafers. ASSET#3949
Zygo 8100 Inspection System	Wavefront Analyzer - Capable 3" to 8" Wafers. ASSET#3225
Zygo 8800 Inspection System	Wavefront Analyzer - Capable 3" to 8" Wafers

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